The form ation, ripening and stability of epitaxially strained island arrays

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W e study the form ation and evolution of coherent islands on lattice m ism atched epitaxially strained Im s. Faceted islands form in Im s with an isstropic surface tension. Under annealing, these islands ripen until a stable array is form ed, with an island density which increases with Im thickness. Under deposition, an island shape transition occurs, which leads to a bim odal island size distribution. In Im s with isotropic surface tension we observe continual ripening of islands above a certain Im thickness. A stable wavy morphology is found in thinner Im s.

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Coherent (dislocation-free) islands form to relieve the strain associated with lattice m ism atched heteroepitaxial thin In s. Their subsequent self-assembly into periodic arrays is of great interest as the arrays can be used to create quantum dot structures of in portance in sem iconductor and optoelectronic devices. Such island arrays must have a narrow size distribution in order to be of use in applications. Of particular interest is whether the island arrays that form are energetically stable or metastable con gurations that will ripen. Here we show in annealing simulations, that anisotropy in surface tension is necessary for the form ation of a stable (roughly periodic) array with a narrow size distribution. Moreover, we show that the presence of a cusp in the surface energy is essential for reproducing the experim entally observed increase in island density with increasing Im thickness. We also show that a single cusp in the surface energy (along with elastic relaxation) is su cient in order to explain the island shape transition [1], which occurs in grow th experim ents, and the associated bim odal island size distribution.

We study the evolution of an elastically isotropic system using continuum theory. The surface of the solid is at y = h(x;t) and the lm is in the y > 0 region with the

In -substrate interface at y = 0. The system is modeled to be invariant in the z-direction, and all quantities are calculated for a section of unit width in that direction. This is consistent with plane strain where the solid extends in nitely in the z-direction and hence all strains in this direction vanish.

W e assume that surface di usion is the dom inant m ass transport mechanism, leading to the following evolution equation [2]:

$$\frac{\partial h}{\partial t} = \frac{D_s}{k_B T} \frac{\partial}{\partial x} \frac{\partial}{\partial s}; \qquad (1)$$

where D_s is the surface di usion ∞ e cient, is the number of atom s per unit area on the solid surface, is the atom ic volume, T is the tem perature, k_B is the Boltzmann constant, s is the arc length and is the chemical potential at the surface.

In our previous work $[\beta,4]$ we showed that can be expressed as

$$- = e() + \frac{df_{el}^{(0)}}{dh} + \frac{1}{2}S_{ijkl\ ij\ kl} + \frac{1}{2}S_{ijkl\ ij\ kl} ; (2)$$

where is surface curvature, is the angle between the norm all to the surface and the y-direction and e() =

()+ $\theta^2 = \theta^2$ is the surface sti ness (with () being the surface tension). S_{ijkl} are the compliance coe cients of the m aterial, $_{ij}$ is the total stress in the m aterial, $_{ij}^{(0)}$ is the mism atch stress in the zero strain reference state and $f_{el}^{(0)}$ (h) is the reference state free energy per unit length in the x-direction. The reference state is de ned as a at lm of thickness h con ned to have the lateral lattice constants of the substrate.

Linear stability analysis predicts that a at Im thinner than the linear wetting layer thickness, h_c , is stable at all perturbation wavelengths and is marginally stable to perturbations of wavelength $_c$ for thickness h_c . The expressions for h_c and $_c$ are given in [3,4]. Above h_c the at Im is unstable to a larger and larger range of wavelengths $_+$ until for in nitely thick Im s the Im is unstable to all perturbations of wavelengths larger than = c=2.

W e simulated the surface evolution given by Eqs. (1) and (2) using the numerical scheme described in our earlier work [4]. W e used the cusped form of surface tension given by B onzel and P reuss [5], which shows faceting in a free crystal at 0 ; 45 and 90 . $df_{el}^{(0)}(h)=dh$ was obtained from ab-initio quantum mechanical calculations of Si_{1 x} G e_x grown on Si(001) (for details see [6]). All our simulations start from a random ly perturbed at lm with an initial thickness denoted by C.

W hen perturbations larger than a critical amplitude [3,4,6] are applied to a at m, faceted islands develop in the lm during both annealing and grow th, as illustrated in Fig.1. The lm rst becomes unstable at wavelength

50 (0)=M "², where M is the plain strain modulus and " is the lattice mism atch. The islands which form from this perturbation typically have a width of about 10% of the unstable wavelength. Both the critical wavelength and the faceted island widths scale as " ²,

as observed in experiments [7{10] in which islands develop from long ripple like structures (corresponding to our model of plane strain).

All results discussed henceforth refer to Ge/Si(001) though the same trends were seen in $Ge_{0:5}Si_{0:5}/Si(001)$. Islands form in a 'chain-reaction ripple' e ect (i.e., islands tend to develop near other islands) as is illustrated in F ig. 1. This mode of grow th has also been observed in experiment [11,12]. The ripple e ect occurs because the grow th of the island destabilizes the at lm at its boundaries. A fler initial island form ation we observe island ripening occurring over much longer time scales (about 50 times longer).

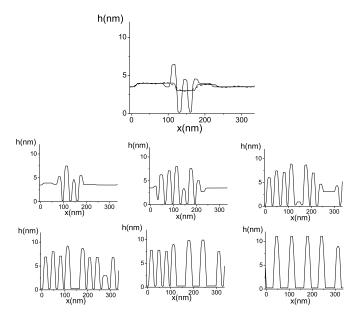


FIG.1. Evolution of a random perturbation on a 25 m onolayer thick Ge lm on a Si(001) substrate. In the rst graph the dashed line is the initial perturbation, the thin solid line is the surface at t= 0.005s and the thick solid line is the surface at t= 0.032s. The second to sixth graphs show the surface at tim es t= 0.044s, 0.068s, 0.094s, 0.123s and 2.181s. The nal graph is the stable steady state island array. Note the ripple e ect in island form ation and the later island ripening leading to a stable island array.

D uring annealing the islands are fully faceted. Their tops are faceted at 0 and their sides at 45. This shape is preserved as the islands grow, i.e., the islands m aintain a xed diam eter-height ratio (as seen in experiment [7,13{15] and theory [16]). During deposition, on the other hand, an interesting transition is observed in the island shape. Initially, the islands are fully faceted as during annealing. However, when the islands reach a certain diam eter, they stop growing laterally and only vertical growth occurs. This critical diam eter is about 40nm for G e islands grown on a Si(001) substrate (during annealing we never observed islands which exceeded this diam eter). Thus the islands become talland narrow, and

their sides are steeper than 45 . This shape transition is observed experimentally [1,14,17,18], and is sometimes referred to as the \pyram id-to-dome transition". The driving force behind it is the increased elastic relaxation experienced by tall-narrow islands. Theoretical equilibrium calculations with isotropic surface tension [19] show a continuous increase in island aspect ratio with increasing island volume, as elastic e ects dom inate surface tension e ects. The sharp rather than sm ooth transition in grow th m ode we observe is due to the anisotropic nature of the surface tension and in particular the presence of a facet at 45 . Note that contrary to existing explanations of the island shape transition (see e.g. [20]), the transition occurs without an additional facet orientation at a larger angle.

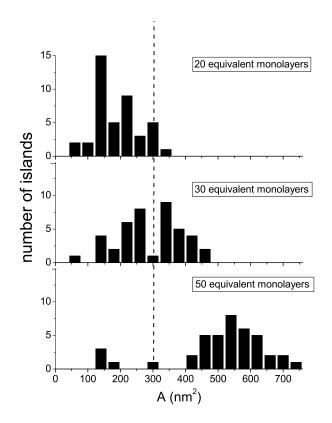


FIG.2. Distribution of island cross-sectional area, A (recall that islands are in nitely long in the z-direction), during directed deposition of G e on a Si(001) substrate. The rate of deposition is 5.2nm/s, and the initial lm height is 10 m onolayers. The dashed vertical line shows the separation between the early growth m ode in which the island height-width ratio is preserved and the later vertical growth m ode.

The transition in island shape and growth mode is clearly re ected in the size distribution shown in Fig. 2. Narrow island size and spacing distributions are seen during early deposition (see Fig. 2, 20 equivalent monolayers). These narrow distributions are observed in many experiments $[1,7,14,15,18,21\{23]$. During later deposition (30 equivalent monolayers) a bimodal distribution forms as some of the islands pass from the fully faceted to the tall-narrow shape. At later times (e.g. 50 equivalent monolayers) nearly all islands have the tall-narrow shape. At this stage the distribution becomes quite sym – metric and evolves at a xed distribution width (increasing its mean). Sim ilar results were observed in experiment [1,14,17,18].

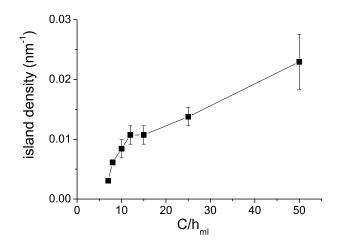


FIG.3. Island density in a stable array of Ge islands on a Si(001) substrate after ripening has ended. C is the initial at lm thickness, and $h_{m\,1}$ is the thickness of one monolayer. The error bars refer to the span of island densities observed with di erent initial surface morphologies.

One of our central observations is that annealing of a perturbed at In with anisotropic surface tension leads to the form ation of a stable array of islands. This result is consistent with several experimental systems [21,24{26], and is in contrast with Im s of isotropic surface tension where the islands ripen inde nitely. Theoretical studies also predict stable island arrays [27{30]. The crucial term in determining the stability of an island array apart from anisotropic surface tension and a Im -substrate interaction is the presence of an elastic contribution due to island edges. This contribution is automatically present in our calculations and does not need to be introduced separately. Theoretical works that ignore this term [22,31] predict continuous ripening.

O ur simulations show that the density of islands in the stable array increases with increasing Im thickness (see Fig. 3). An increase in island density with Im thickness has also been seen in m any experiments [15,23,26,32(35]. Indeed M iller et al. [26] and K am ins et al. [35] perform ed annealing experiments and Leonard et al. [32] perform ed experiments with very small deposition rates. These three experiments clearly show the increase in island density as Im thickness increases. This result was predicted by D aruka and B arabasi [28] in m inim al energy equilib

rium calculations. Here we show for the st time that the increase in island density also results from evolution simulations. This observation is particularly important, since other evolution studies [29] predicted a decrease in island density with increasing Im thickness. We believe this is due to the smooth form of surface tension used in [29]. Indeed when we carried out simulations with a smooth form of surface tension similar to that used in [29], we also observed a decrease in island density. This clearly demonstrates the importance of using a cusped form of surface tension to accurately model evolution of faceting surfaces.

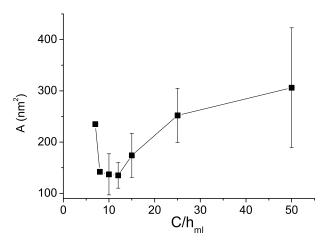


FIG.4. A verage island cross-sectional area, A (recall that islands are in nitely long in the z-direction), in a stable array of G e islands on a Si(001) substrate after ripening has ended. C is the initial at lm thickness, and $h_{m\,1}$ is the thickness of one m on olayer. The error bars refer to the standard deviation in island sizes observed throughout all sam ples of the sam e lm thickness.

As can be seen in Fig. 4, the island size also shows a slight increase with increasing Im thickness, with islands increasing in width from 25nm to 40nm, and crosssectional area from 100nm^2 to 500nm^2 (recall that islands are in nitely long in the z-direction). The island size at 7 m onolayers is larger than expected due to nite size e ects. Note that even the smallest islands have a nite non-zero size. Experiments indeed see islands forming only above a certain size which increases with increasing Im thickness [15,21{23,35]. However, as the experim ents which were perform ed for annealing and showed stable island arrays tended not to vary the Im thickness, it is di cult to compare our results with experim ental observations. Our result is in accordance with that predicted in equilibrium calculations by Daruka and Barabasi [28].

W hen surface tension is isotropic, corresponding to Im s above the roughening transition temperature, at Im evolution during annealing is very di erent from that described above. Perturbations in $\ln s$ thinner than $h_{\rm b}$ decay, and at $\ln s$ with thickness $h < h < h_c + ,$ where 1 m onolayer, develop a stable sm ooth wavy m orphology at $_{\rm c}$. That is, perturbations of other wavelengths decay and perturbations of wavelength $_{\rm c}$ grow to a nite am plitude. This is a mode of grow th neither seen nor predicted before. Stable, non at m orphology, has previously only been predicted for faceting $\ln s$ [27[30]. In fact, other groups maintain that isotropic $\ln s$ should be unstable to ripening [29,30,36,37]. W hile $\ln s$ are linearly unstable to perturbations of wavelengths

 $_+$, our sin ulations show that the nonlinearity stabilizes the growth of wavelengths close to and $_+$. As a result the growth of the perturbation saturates and stops at a nite amplitude, as seen by Spencer and M eiron [38] for in nitely thick lm s. When lm s are su ciently close to the linear wetting layer thickness, the range of nonlinear saturation extends over the entire range of linearly unstable wavelengths and so a stable wavy m orphology is observed. For lm s thicker than $h_{\rm e}$ + , initially a wavy structure at the most unstable wavelength form s. The hills of these waves then ripen on larger and larger length scales, until isolated islands are left that continue ripening.

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